

Abstract

[Problem] To provide a technology with which coating uniformity can be enhanced.

[Solution] A semiconductor manufacturing apparatus includes:
5 a coater having a syringe in which paste is stored, a nozzle holder provided at the tip of the syringe, a nozzle provided in the nozzle holder, and a heating unit for heating the nozzle holder, and applying the paste onto an object to be coated; and a control unit so configured that a temperature
10 of the nozzle holder is adjusted by the heating unit and the paste is applied from the nozzle onto the object to be coated.

[Selected drawing] FIG. 6